

<b>Notice of References Cited</b>	Application/Control No. 10/721,331	Applicant(s)/Patent Under Reexamination WADA, KENJI	
	Examiner Heather A. Doty	Art Unit 2813	Page 1 of 1

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	C	US-6,720,641	04-2004	Birdsley et al.	257/621
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**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT DOCUMENTS**

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	U	S. Wolf and R.N. Tauber, Silicon Processing for the VLSI Era, v. 1, 2nd edition, Lattice Press, 2000, pg. 784.
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.